

SEMI-AUTOMATED COATING/DEVELOPING PLATFORM

SUSS RCD8

RESIST COAT AND DEVELOP PLATFORM

The RCD8 coat and develop platform can be custom tailored anywhere from e.g. a basic manual spin coater to a semi automated GYRSET® enhanced coater or puddle developer tool, serving for daily R&D work up to small scale production. Whenever changes are required over time, this versatile tool can be field upgraded with various options to perfectly match your future needs.

With its large variety of available chucks and configurations, literally all kind of substrate materials and shapes can be coated and developed on the RCD8. The platform can be equipped with various well proven dispense line and pump configurations for handling resists with viscosities from <1 cps up to 55 000 cps.

Optionally, the tools can be integrated into a LabCluster, which allows a big variety of different configuration options, consisting of coater, developer, hotplate and vapor primer modules.

UNIQUE GYRSET®

As an additional option the patented GYRSET® rotating closed cover coating technology can be integrated into the RCD8 spin coating module. For various photoresists and applications, the GYRSET® technology enables a wider process window and coating without backside contamination. Furthermore, square substrates and pieces can be coated all the way to the corners with a homogenous resist thickness.

SOFTWARE

The standard software installed on the RCD8 platform is production proven and already installed on hundreds of SUSS systems worldwide. The control software is based on Windows 7 and is shared with all other automated SUSS coating platforms allowing a flawless switch of systems.

RCD8 HIGHLIGHTS

- + Available as coater or developer
- + Maximized application variety for lowest cost of ownership
- + Easy transfer of processes to a SUSS production tool due to compatible design with ACS200 Gen3 platform
- + All options are field upgradeable



The touchscreen GUI (Graphical User Interface) monitors performance and status of the entire machine and tanks. With the intuitive software the operation of the tool is easy to acquire. The generation of process recipes is simplified by point-and-click ease.



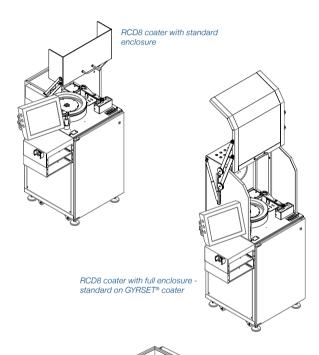


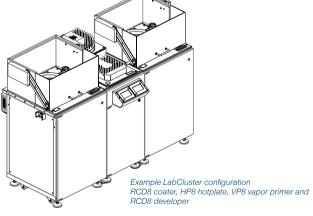


SEMI-AUTOMATED COATING/DEVELOPING PLATFORM

SUSS RCD8

TECHNICAL DATA





GENERAL	
Substrate Size	2" to 200 mm round, 2" to 150 mm square
Substrate Handling	manual, with lift pins
User Interface	SUSS MMC Tool Control on Windows 7, industrial PC with touch screen control
Max. # of Recipes	>10000
Max. # of Process Steps	50
Utilities	230 V/400 V, 16 A, 50 Hz/60 Hz, vacuum not needed, produced internally by N2 or CDA
MODULE: OPEN BOWL C	OATER
Spin Speed Max	10 000 rpm* ± 1 rpm (with safety hood), 12 000 rpm upon special request
Spin Acceleration	1-7000 rpm/s*
Bowl Material	nickel-plated aluminium
Dispense Arm	dispense arm with up to 2 photoresist lines up to 2 solvent lines optional: motorized syringe
MODULE: GYRSET® COA	TER
Spin Speed Max	3000 rpm* ± 1 rpm with GYRSET®
Spin Acceleration	1-3000 rpm/s*
Bowl Material	nickel-plated aluminium
Cover Options	3 different sizes in low and high versions
MODULE: PUDDLE DEVE	LOPER
Spin Speed Max	10 000 rpm* ± 1 rpm (with safety hood)
Spin Acceleration	1-7000 rpm/s*
Bowl Material	polyethylene
Dispense Arm	dispense arm with up to 2 developer lines and

^{*} substrate and chuck dependent

Data, design and specification depend on individual process conditions and can vary according to equipment configurations. Not all specifications may be valid simultaneously. Illustrations, photos and specifications in this brochure are not legally binding. SUSS MicroTec reserves the right to change machine specifications without prior notice.

deionized water line



Visit www.suss.com/locations for your nearest SUSS representative or contact us: SÜSS MicroTec SE

+49 89 32007-0 · info@suss.com

